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PATENT
Attorney Docket No.: 019930-002310US
Client Reference No.: A1292

On December 30, 2003

TOWNSEND and TOWNSEND and CREW LLP

Kevin L. McNeill

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Bevan Staple et al.

Application No.: 10/632,698

Filed: August 1, 2003

For: METHOD FOR REDUCING
LEACHING IN METAL-COATED
MEMS

Examiner: Not yet known

Art Unit: 1762

INFORMATION DISCLOSURE
STATEMENT UNDER 37 CFR §1.97 and
§1.98

Commissioner for Patents
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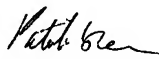
Sir:

The references cited on attached form PTO/SB/08A and PTO/SB/08B are being called to the attention of the Examiner. This application is a continuation application of and relies on U.S. Appl. No. 09/799,916 filed March 5, 2001 (the "parent application") for an earlier effective filing date under 35 U.S.C. § 120. All of the references were submitted to or cited by the Patent and Trademark Office in the parent application. Therefore, pursuant to 37 CFR § 1.98(d), copies of the references are not enclosed. It is respectfully requested that the cited references be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

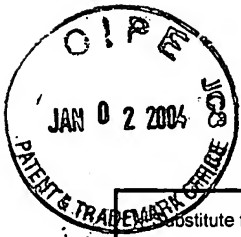
As provided for by 37 CFR 1.97(g) and (h), no inference should be made that the information and references cited are prior art merely because they are in this statement and no representation is being made that a search has been conducted or that this statement encompasses all the possible relevant information.

Applicant believes that no fee is required for submission of this statement. However, if a fee is required, the Commissioner is authorized to deduct such fee from the undersigned's Deposit Account No. 20-1430. Please deduct any additional fees from, or credit any overpayment to, the above-noted Deposit Account.

Respectfully submitted,


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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Complete if Known	
				Application Number	10/632,698
				Filing Date	August 1, 2003
				First Named Inventor	Bevan Staple
				Art Unit	1762
				Examiner Name	Not yet known
Sheet		of		Attorney Docket Number	019930-002310US

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code ² (if known)			
	AA	US-			
	AB	US-			

FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)				
	AC							<input type="checkbox"/>
	AD							<input type="checkbox"/>

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	AE	ARK-CHEW WONG, JOHN R. CLARK and CLARK T.-C. NGUYEN, Anneal-Activated, Tunable 68 MHz Micromechanical Filters, Center for Integrated Microsystems, Dept. of Electrical and Computer Science, University of Michigan, Ann Arbor, Michigan 48109, Transducers '99, June 7-10, 1999, pp. 1390-1393, Sendai, Japan	
	AF	ASHUF, C.M.A., et al., "Galvanic porous silicon formation without external contacts," Sensors and Actuators 74, June 1999, pp. 118-122	
	AG	TORCHEUX, L., et al., "Electrochemical Coupling Effects on the corrosion of Silicon Samples in HF Solutions," J. Electrochem. Soc., Vol. 142, No. 142, No. 6 June 1995, pp. 2037-2046.	
	AH	KELLER, CHRISTOPHER GUILD, "Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion," dissertation submitted in the graduate division of the University of California, Berkeley, Fall 1998.	
	AI	MULLER, LILAC, "Gimballed Electrostatic Microactuators with Embedded Interconnects," dissertation submitted in the graduate division of the University of California, Berkeley, Spring 2000.	

Examiner Signature		Date Considered	
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* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.